

### SWARNANDHRA COLLEGE OF ENGINEERING AND TECHNOLOGY

(Autonomous)

Narsapur, West Godavari District, A.P. 534280

### DEPARTMENT OF MECHANICAL ENGINEERING

## **LESSON PLAN**

Course Course Title		Semester		Branches	Contact Periods /Week	Academ ic Year	Date of commencement of Semester		
20RB7E11 Mechanical Systems		VII		Mechanical Engineering	5	2025-26	09-06-2025		
COUR	SE OU	ITCOMES							
1	Classify various micro electro mechanical system components.[K2]								
2	Demo	nstrate mechani	cal sens	sors an	d actuators.[K2]				
3	Describe thermal sensors and actuators.[K2]								
4	Describe magnetic sensors and actuators. [K2]								
5	Illustrate micro-opto-electro mechanical systems. [K2]								
UNIT	Outcomes / Bloom's Level		Topi cs No.	Topics/Activity		Text Book / Referen ce	Cont act Hou r	Delivery Method	
				IN	TRODUCTION				
	Classify various micro electro		1.1	Introduction about Micro Electro Mechanical Systems			T1, T2	1	Chalk & Talk, PPT & Think share
			1.2	MEMS history and development  Micro Machining			T1, T2	1	
			1.3				T1, T2	1	
I			1.4	Lithography Principles & Methods			T1, T2	1	
			1.5	Structural and Sacrificial Materials			T1, T2	1	
	mechanical system components. [K2]	1.6	Thin Film Deposition			T1, T2	1		
		onents. [112]	1.7	Impurity Doping & Etching			T1, T2	1	Pair
		1.8	Surface Micro machining			T1, T2	1		
			1.9	Wafer Bonding			T1, T2		1
			1.10	IGA			T1, T2	1	
	Total							10	



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	ME	CHAN	ICAL SENSORS AND ACTUATO	ORS			
II	Demonstrate mechanical sensors and actuators. [K2]	2.1	Principles of sensing and actuation: beam and cantilever	T1, R1	1		
		2.2	Capacitive sensor	T1, R1	1	Chalk & Talk, & Video	
		2.3	Piezo electric sensor	T1, R1	1		
		2.4	Strain sensor, pressure & flow sensor	T1, R1	1		
		2.5	Pressure measurement by micro phone	T1, R1	1		
	and actuators. [122]	2.6	MEMS gyroscope	T1, R1	1		
		2.7	Shear mode piezo actuator	T1, R1	1		
		2.8	Gripping piezo actuator	T1, R1	1		
		2.9	Inchworm technology	T1, R1	1	1	
			Total		09		
	Т	HERM	IAL SENSORS AND ACTUATOR	S			
		3.1	Heat transfer processes	T1,T3	1		
	Describe thermal sensors and actuators. [K2]	3.2	Thermistors & Thermos devices	T1,T3	1		
		3.3	Thermocouple	T1,T3	1	Chalk & Talk, & Video	
		3.4	Micro machining	T1,T3	1		
		3.5	Peltier effect heat pumps	T1,T3	1		
TTT		3.6	Thermal flow sensors	T1,T3	1		
III		3.7	Micro hot plate gas sensors	T1,T3	1		
		3.8	Shape memory alloys	T1,T3	1		
		3.9	U shaped horizontal and vertical electro thermal sensor	T1,T3	1		
		3.10	Micro spring thermal actuator	T1,T3	1		
		3.11	Data storage cantilever	T1,T3	1		
Total							
	M	AGNE	TIC SENSORS AND ACTUATOR	RS			
		4.1	Magnetic sensing and detection	T1,R1	1		
		4.2	Magneto resesitive sensors	T1,R1	1		
		4.3	Halls effect	T1,R1	1		



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IV		4.4	Magneto diodes & transistor	T1,R1	1	Chalk & Talk, & Quiz	
	Describe magnetic sensors and actuators. [K2]	4.5	MEMS magnetic sensor	T1,R1	1		
		4.6	Pressure sensor	T1,R1	1		
		4.7	Magnetic MEMS actuator	T1,R1	1		
		4.8	Directional micro actuator	T1,R1	1		
			Feedback circuit integrated magnetic sensor	T1,R1	1		
Cour	rse Beyond Syllabus		Chemical and Biological sensors	T1	1		
		10					
	MICRO-OPTO-	ELEC	TRO MECHANICAL SYSTEMS				
		5.1	Principle of MOMS technology	T1,T2	1		
	Illustrate micro- opto-electro mechanical systems [K2]	5.2	Properties of light & Light modulators	T1,T2	1	Chalk & Talk, & Video	
		5.3	Beam splitter	T1,T2	1		
		5.4	Micro lens & Micro mirrors	T1,T2	1		
V		5.5	Digital micro mirror device	T1,T2	1		
		5.6	Light detectors	T1,T2	1		
		5.7	Grating light valve and optical switch,	T1,T2	1		
		5.8	Wave guide and tuning	T1,T2	1		
		5.9	Shear stress measurement	T1,T2	1		
Cour	rse Beyond Syllabus		Microfluidic Devices	T1	1		
			Total		10		
	50						
Text E	Books:						
S.No.	AUTHORS, BOOK	TITL	E, EDITION, PUBLISHER, YEAR	OF PUBL	ICAT	ION	
T1	Mahalik N P, MEMS, Tata McGraw-Hill Education (India) Pvt Limited, 2013.						
T2	Rai - Choudhury P, MEMS and MOEMS Technology and Applications, PHI Learning Private Limited, 2009.						
Т3	Nadim Maluf, An Introduction to Micro Electro Mechanical System Design,2 <sup>nd</sup> Edition, Artech House, 2004.						



ii.

iii.

iv.

Course Coordinator

Module Coordinator

Programme

Coordinator

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Refere	ence Books:						
S.No.	AUTHORS, BOOK TITLE, EDITION, PUBLISHER, YEAR OF PUBLICATION						
R1							
	Education, 2017						
R2	Chang Liu, Foundation of MEMS, 2 <sup>nd</sup> Edition, Pearson Education, 2011						
R3	Gerald Urban, Bio-MEMS (Micro systems), Springer.2006						
R4	Mohamed Gad-el-Hak, MEMS Handbook, CRC Press, 2002.						
Web D		n/courses/117105082					
	https://lecturenotes.in/subject/134/micro-electro-mechanical-systems						
		Name	Signature with Date				
i.	Faculty	Dr. R Sanjeev Kumar	255				

Dr. R Sanjeev Kumar Dr. D Bhanu Prakash Dr. M Francis Luther King One ge of Engineen.